

**REMARKS**

Entry of this Amendment in supplement to the Preliminary Amendment filed on March 25, 2004 is respectfully requested.

By the present Amendment, the original claims 1-3 have been replaced by new claims 4-7. These new claims define a plasma etching apparatus or plasma processing apparatus with specific parameters, including a bias power source connected to the electrode used as a sample table for controlling the energy of the ions in the plasma or to obtain a high selective ratio of etching. This is discussed, for example, on page 30, line 16 et seq.

Accordingly, entry of the present Amendment prior to examination is respectfully requested.

If the Examiner believes that there are any other points which may be clarified or otherwise disposed of either by telephone discussion or by personal interview, the Examiner is invited to contact Applicants' undersigned attorney at the number indicated below.

To the extent necessary, Applicants petition for an extension of time under 37 CFR 1.136. Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to the Antonelli, Terry, Stout & Kraus, LLP Deposit Account No. 01-2135 (Docket No. 520.35237CV4), and please credit any excess fees to such Deposit Account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP

By



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